

SEM and DMA (L-314)

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Two apparatus are situated in the room:

Dostopnost

- scanning electron microscope SEM JSM-6060 LV (Jeol, Japan)
- dynamic mechanical analyser DMA Q800 (TA Instruments, USA)



The SEM instrument is designed for surface, morphology and topography studies as well as for determination of particle size. The instrument is also accompanied by a automated sputter coater for fine grained gold coating on sample of non-conductive materials. You can find more about the device [here](#).



The DMA instrument is intended for measuring a viscoelastic properties of various materials (measurements of Tg and secondary transitions, effect of frequency on modulus and Tg, effect of fillings, additives and adhesives, influence of technological processes, stabilities of dimensions, creep, relaxation tension, thermal mechanics, prediction of material response in a wide frequency range and time). You can find more about the device [here](#).



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